

Abstract of the Disclosure

A method and the apparatus of the chemical metal organic vapor epitaxy for the multi-chamber epitaxy layer deposition can process many epitaxy reactions of the organic light-emitting diodes at the same time. More, the different types of epitaxy layers can individual react while passing through the adjustment of time periods. By using the multiple organic light-emitting diodes, it can form multiple epitaxy layers with varying types at the same time. Therefore, it achieves the purpose of shortening the manufacturing process.